NANO4391 - Technology of Plasma

NANO 4391 Technology of Plasma (3 semester credit hours) Plasmas are critical to making the best electronic devices. This class will be an introduction to the technology required to make and use these plasmas. Topics include: high-vacuum technology (gas properties, pumps, pressure gauges, flow-meters, gas composition analysis) and plasma technology (etch, deposition, and lamps). Recommended: ENGR 3341. Prerequisites: ENGR 3300 and (CE 3310) or EE 3310). (Same as EE 4391) (3-0) T